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"Low-Energy Plasma CVD for Epitaxy and In-Situ Doping of Group-IV Semiconductors in Nanoelectronics",
Masao Sakuraba, Hisanao Akima and Shigeo Sato,
Laboratory for Nanoelectronics and Spintronics, Research
Institute of Electrical Communication, Tohoku University
pp.61-115

in

Book Title :

"Chemical Vapor Deposition (CVD): Types, Uses and
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(Edited by Monica Powell, Nova Science Publishers, Inc.,
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